



PATENT

IN THE UNITED STATES PATENT
AND TRADEMARK OFFICE

Applicant: Hyug-Jin Kwon

Serial No.: 10/615,062

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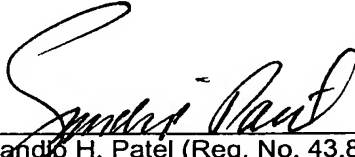
Title: BATCH TYPE ATOMIC LAYER
DEPOSITION APPARATUS
AND IN-SITU CLEANING
METHOD THEREOF

Group Art Unit: 1763

Examiner: Sylvia MacArthur

Attorney Docket No.: 29926/39496

) I hereby certify that this paper is being
) deposited with the United States Postal
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) Mail Stop Amendment, Commissioner for
) Patents, P.O. Box 1450, Alexandria,
) Virginia 22313-1450, on **April 24, 2006**.

) 
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) Attorney for Applicant
)

AMENDMENT "B" AND
SUPPLEMENTAL RESPONSE TO OFFICIAL ACTION

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Dear Sir:

A complete response to the non-final official action dated December 30, 2005, was submitted to the U.S. Patent and Trademark Office on March 30, 2006. In supplemental response to the December 30, 2005, official action, please amend the above-identified patent application as set forth herein. The amendments and remarks presented herein supplement the remarks previously submitted on March 30, 2006, and should be considered along with the previous remarks.

Amendments to the claims begin on page 2 of this paper.

Remarks begin on page 5 of this paper.